

MICROSCOPE

주식회사 제이엔옵틱

2014.11.06

진 재 환

경희대학교 현미경 교육 개요

- 현미경의 종류(배율에 의한 구분)
- 관찰법
 - 명시야, 암시야, 간이편광, DIC, 형광관찰
- 용어설명
 - 대물렌즈
 - NA, WD, 등

배율에 의한 구분

구 분	배율
광학현미경	~ 삼천배
전자현미경	~수십만배
원자현미경	~수천만배

광학 현미경의 관찰방법

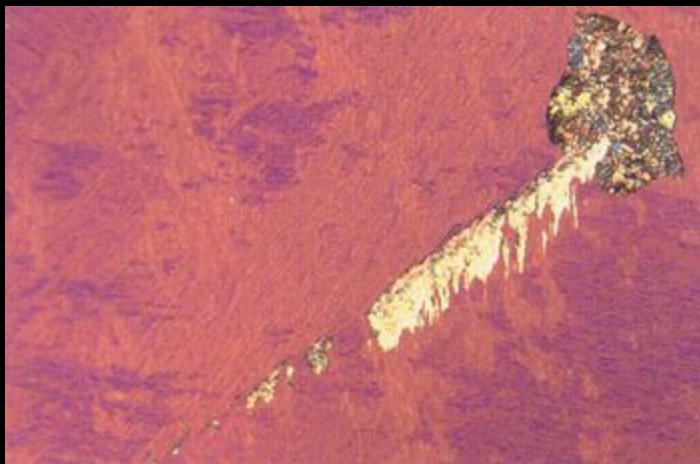
관찰법



Bright field_명시아



Dark Field_암시아

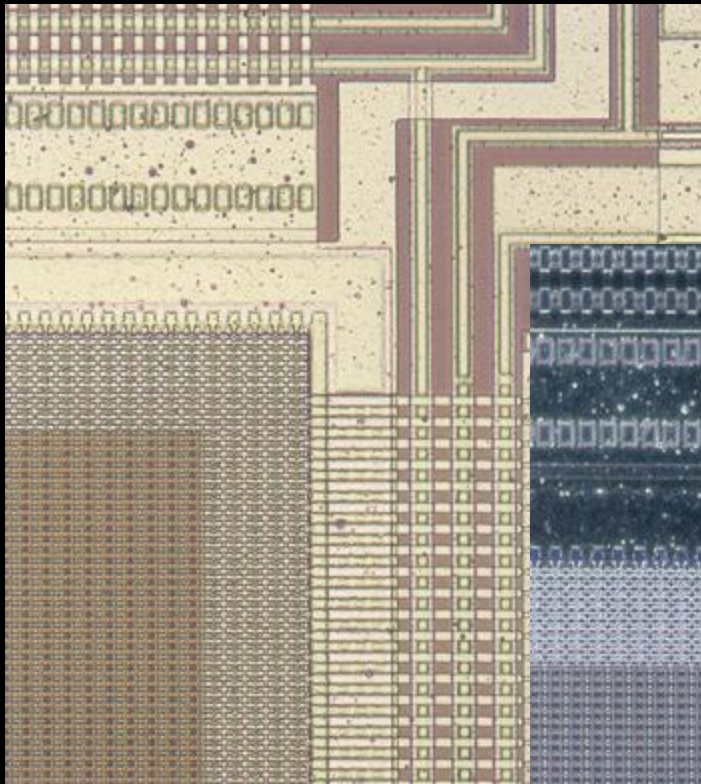


simple polarizing_간이편광

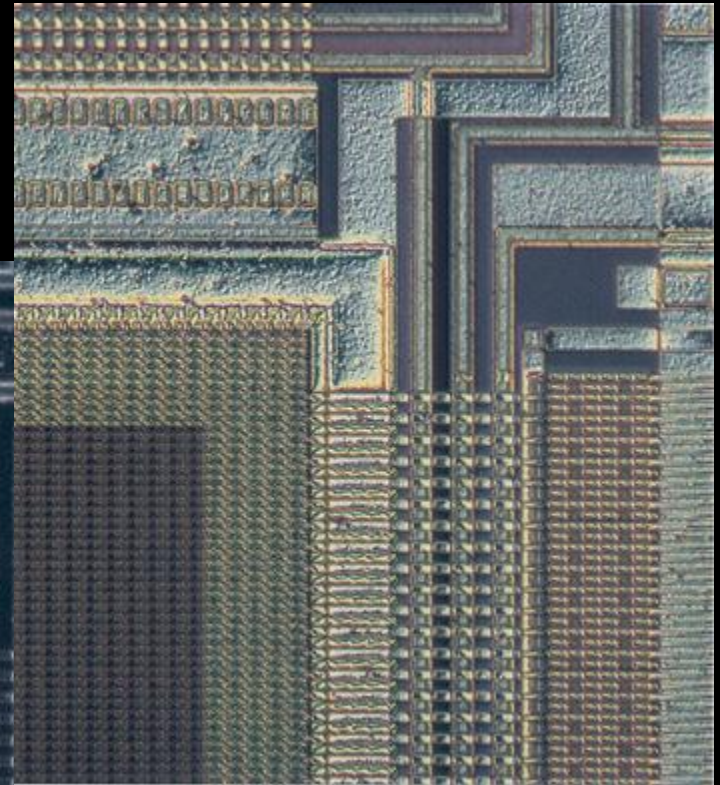


DIC_미분간섭관찰

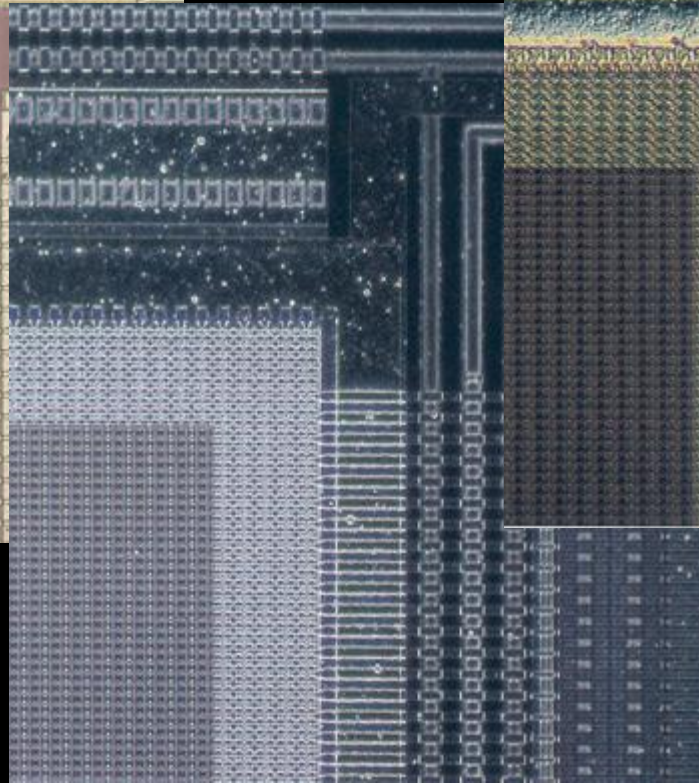
관찰법



Bright Field

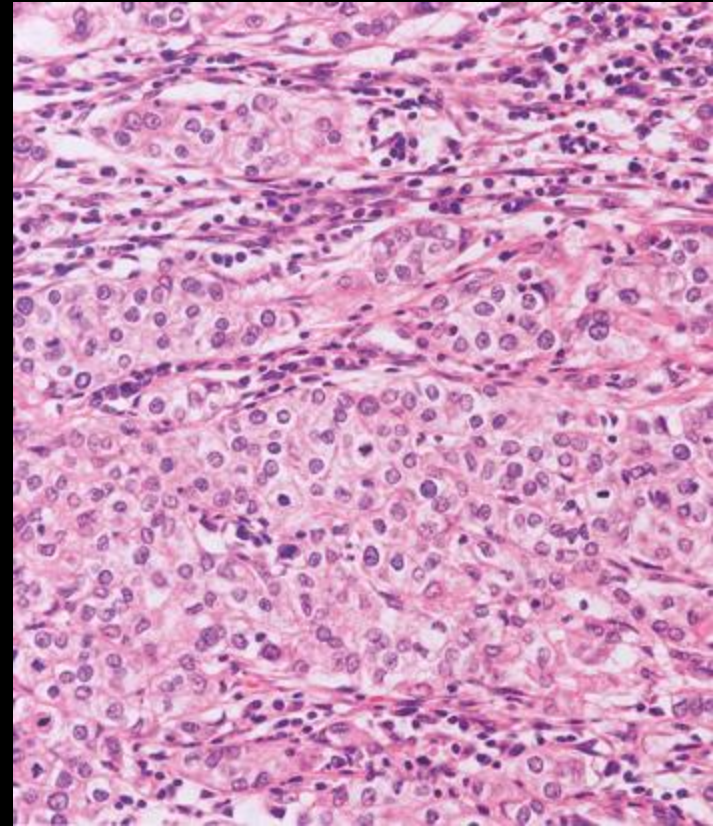
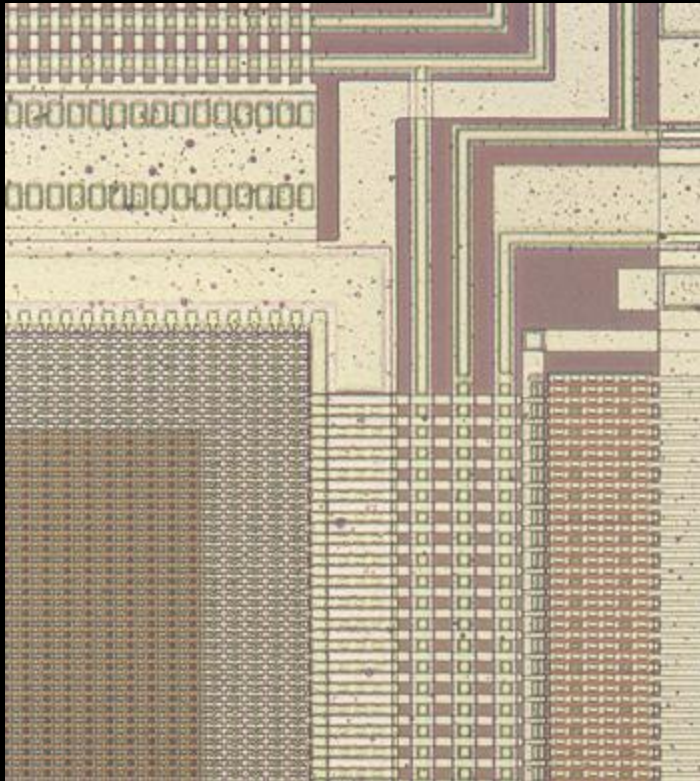


DIC

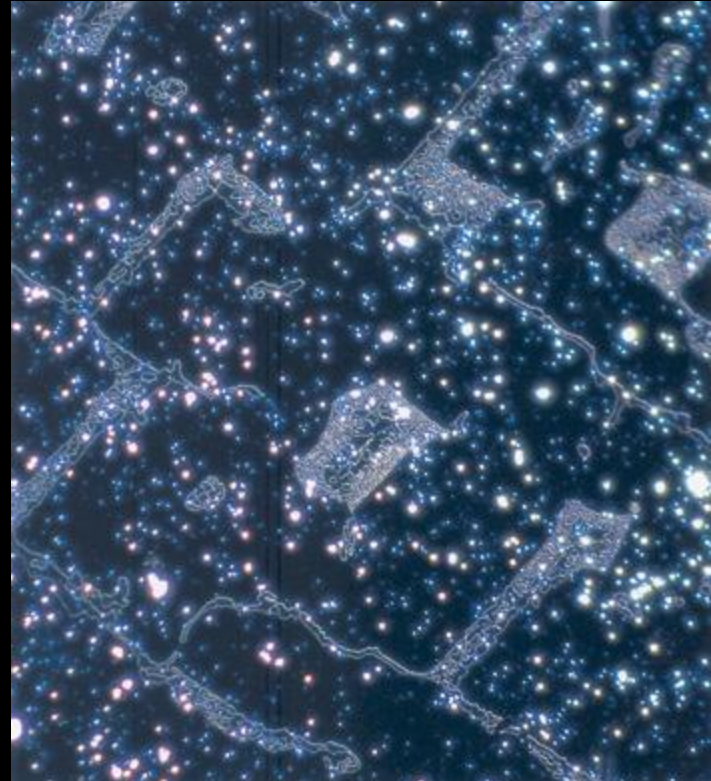
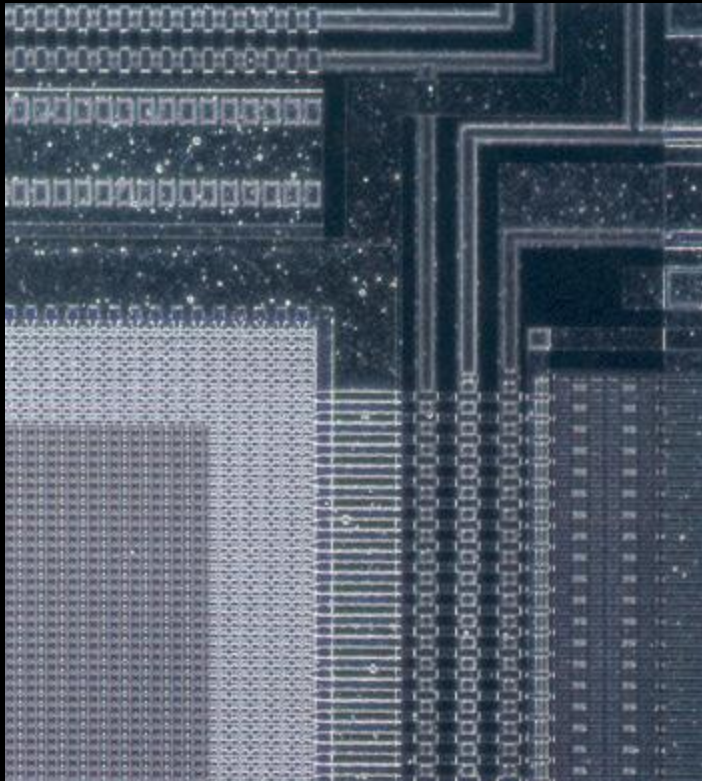


Dark Field

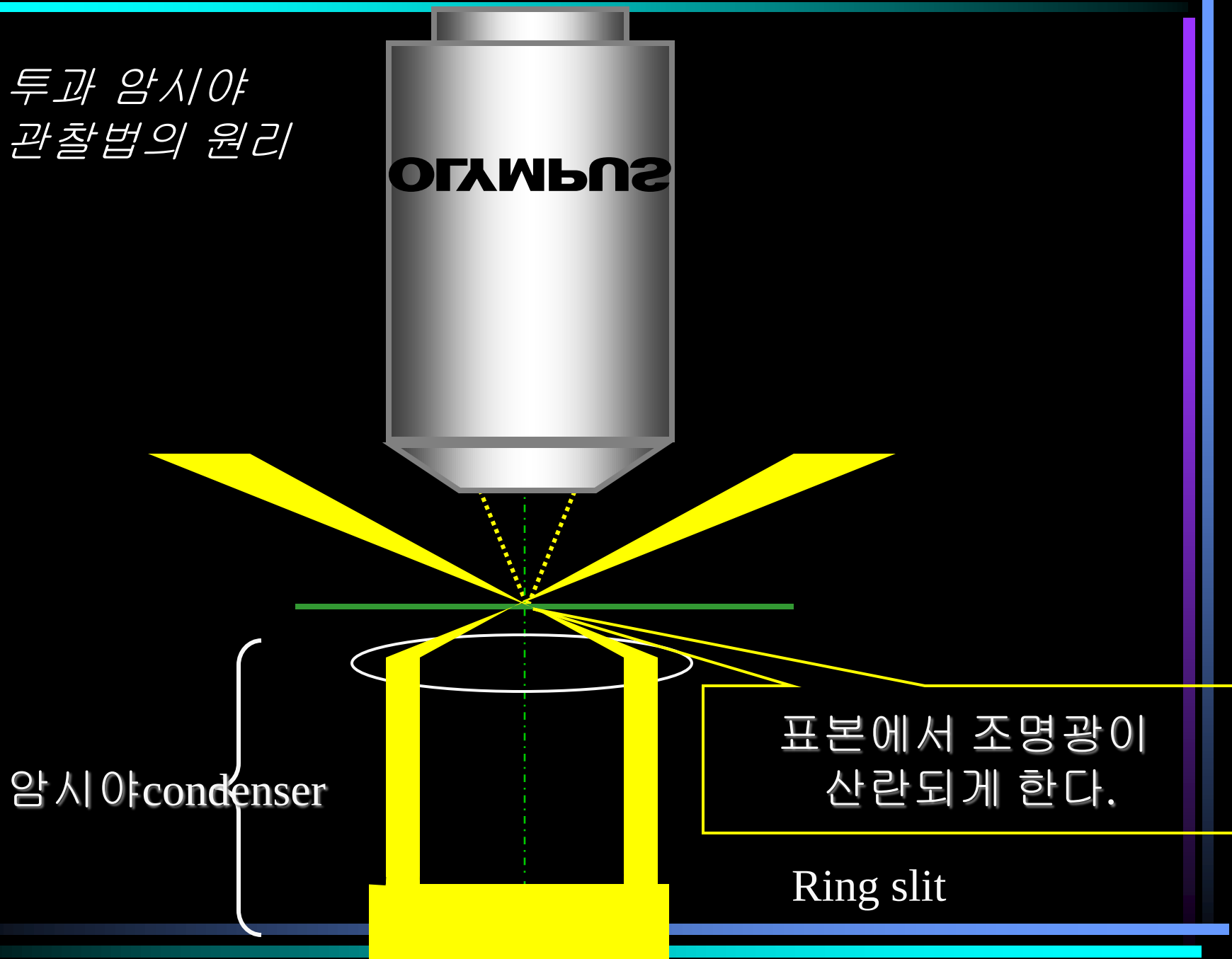
현미경의 관찰법 (Bright Field_명시야)



현미경의 관찰법 (Dark Field_암시야)

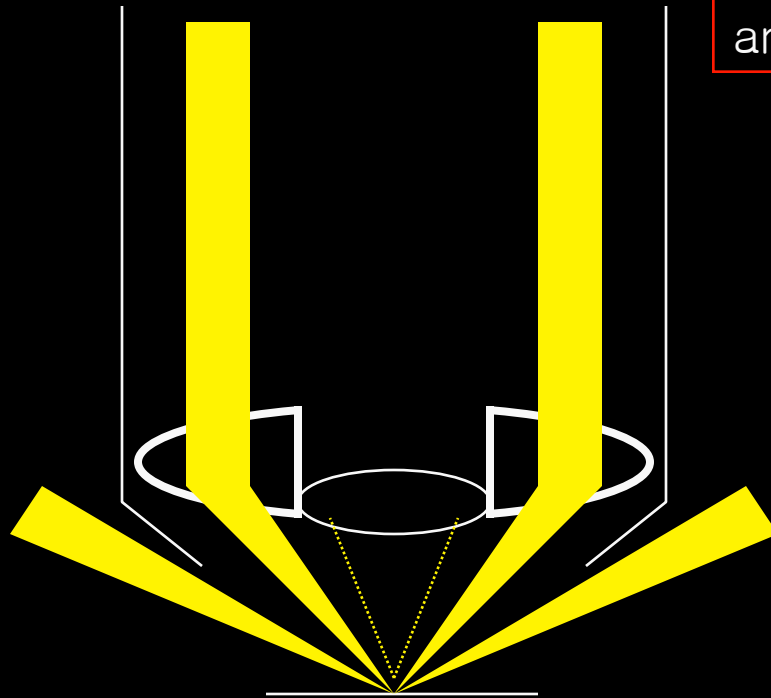


투과 암시야
관찰법의 원리



반사 암시야 관찰법의 원리

Objective for reflected light
darkfield observation

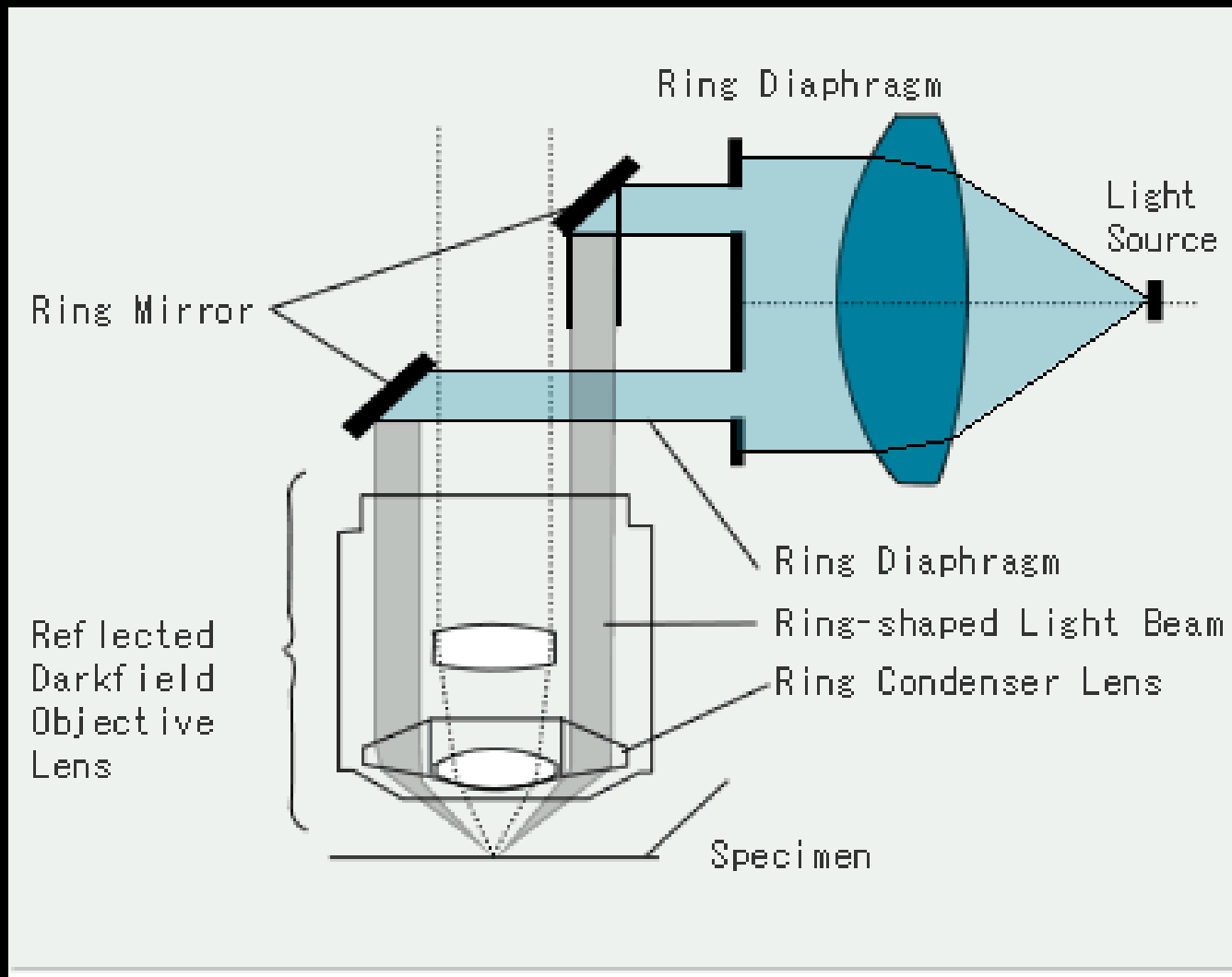


Ring-shaped illumination is radiated on a specimen with the numerical aperture larger than the numerical aperture of the objective.

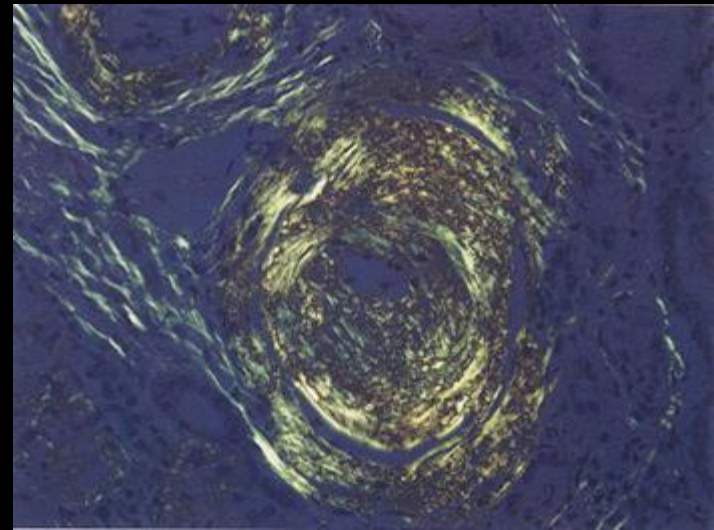
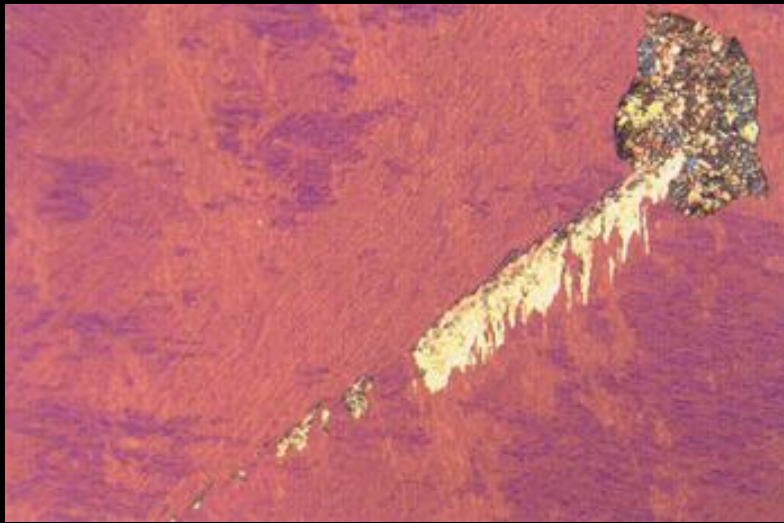
Only scattered or diffracted light is incident on the objective lens to form an image, depending on the type of specimen.

As the illumination numerical aperture increases, the image becomes darker, whereas the detection performance improves.

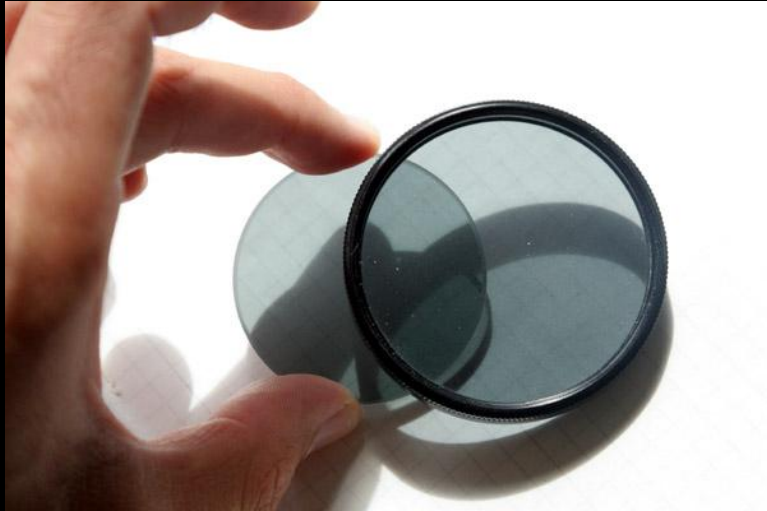
반사 암시야 (Dark field) 관찰 구성



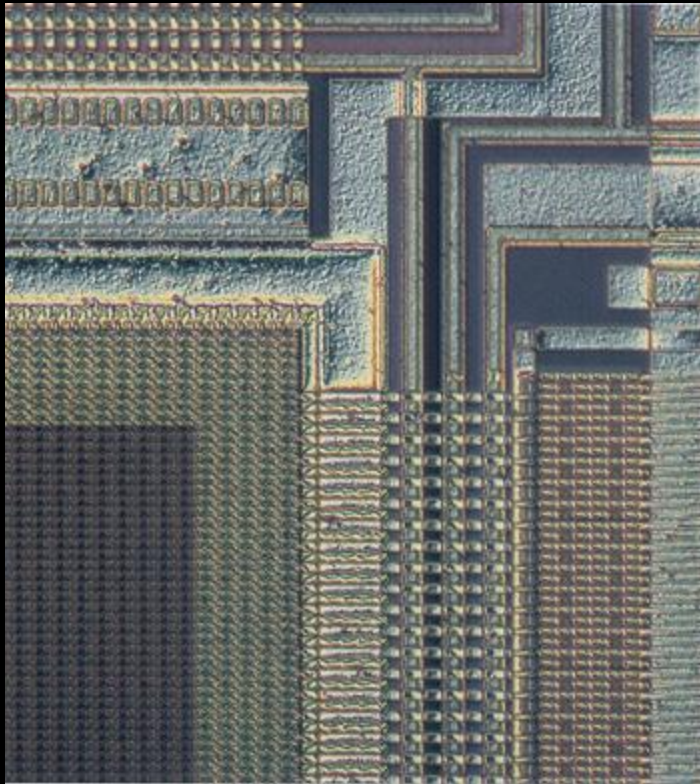
현미경의 관찰법 (Simple Polrazing_간이편광)



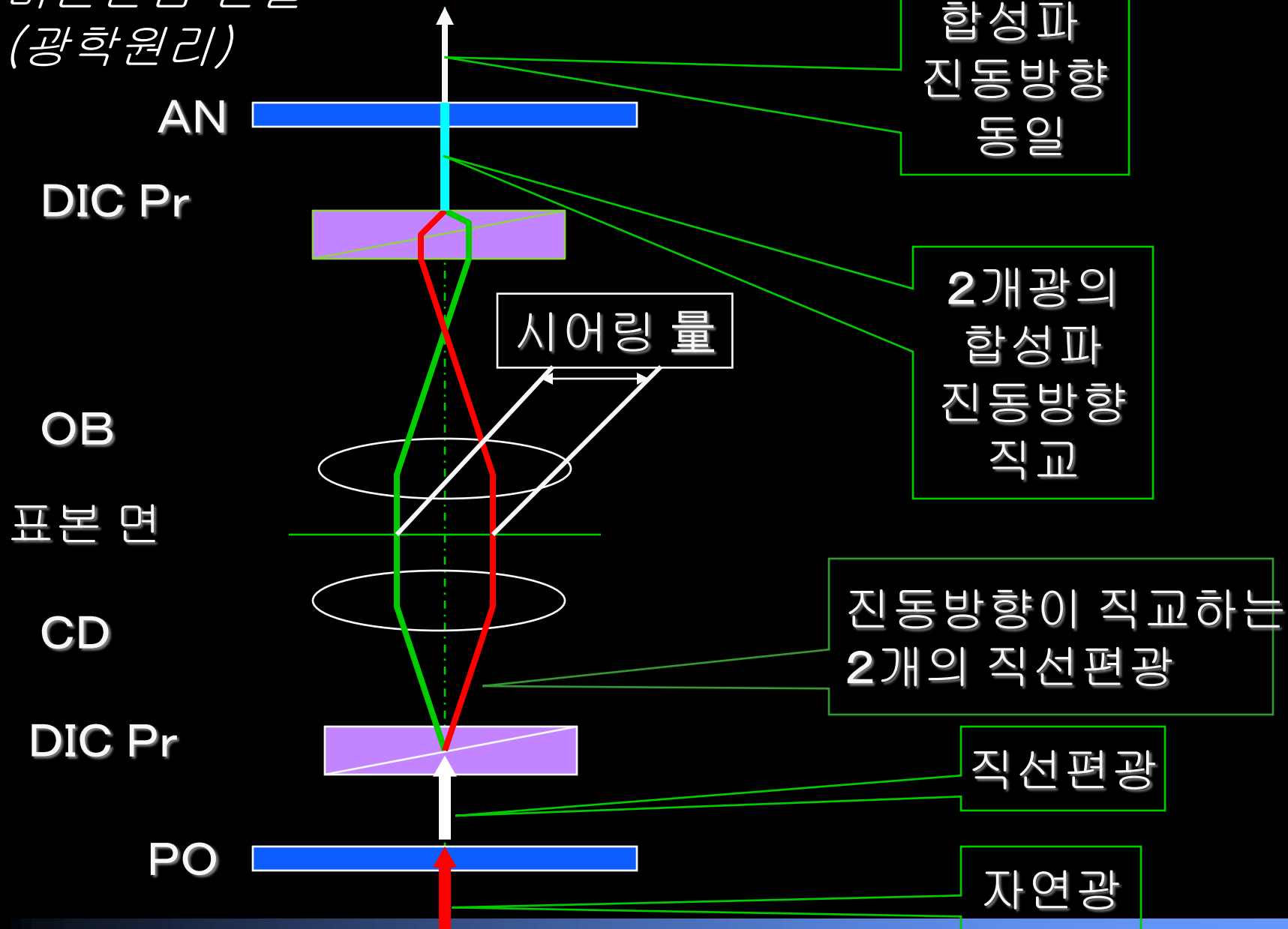
평행 니콜, 직교 니콜



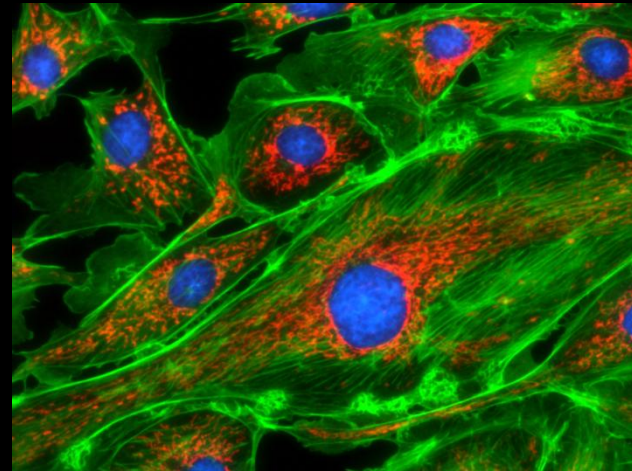
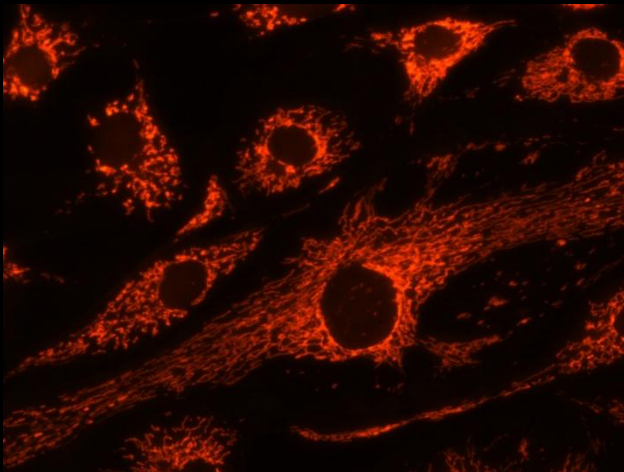
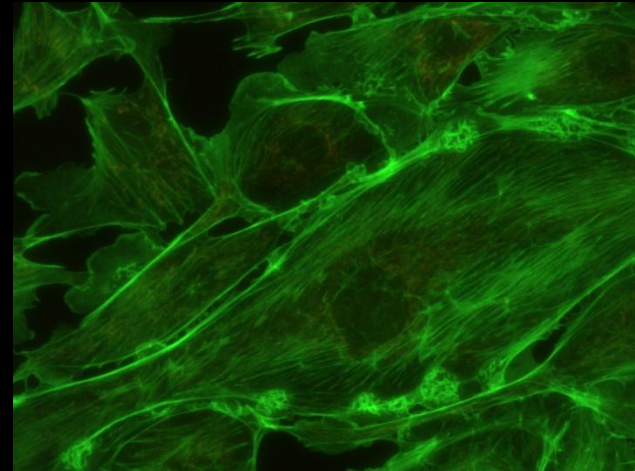
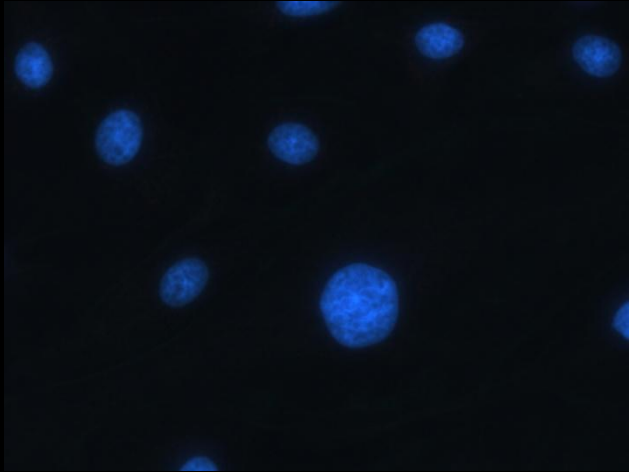
Sample Image(DIC_미분간섭관찰)



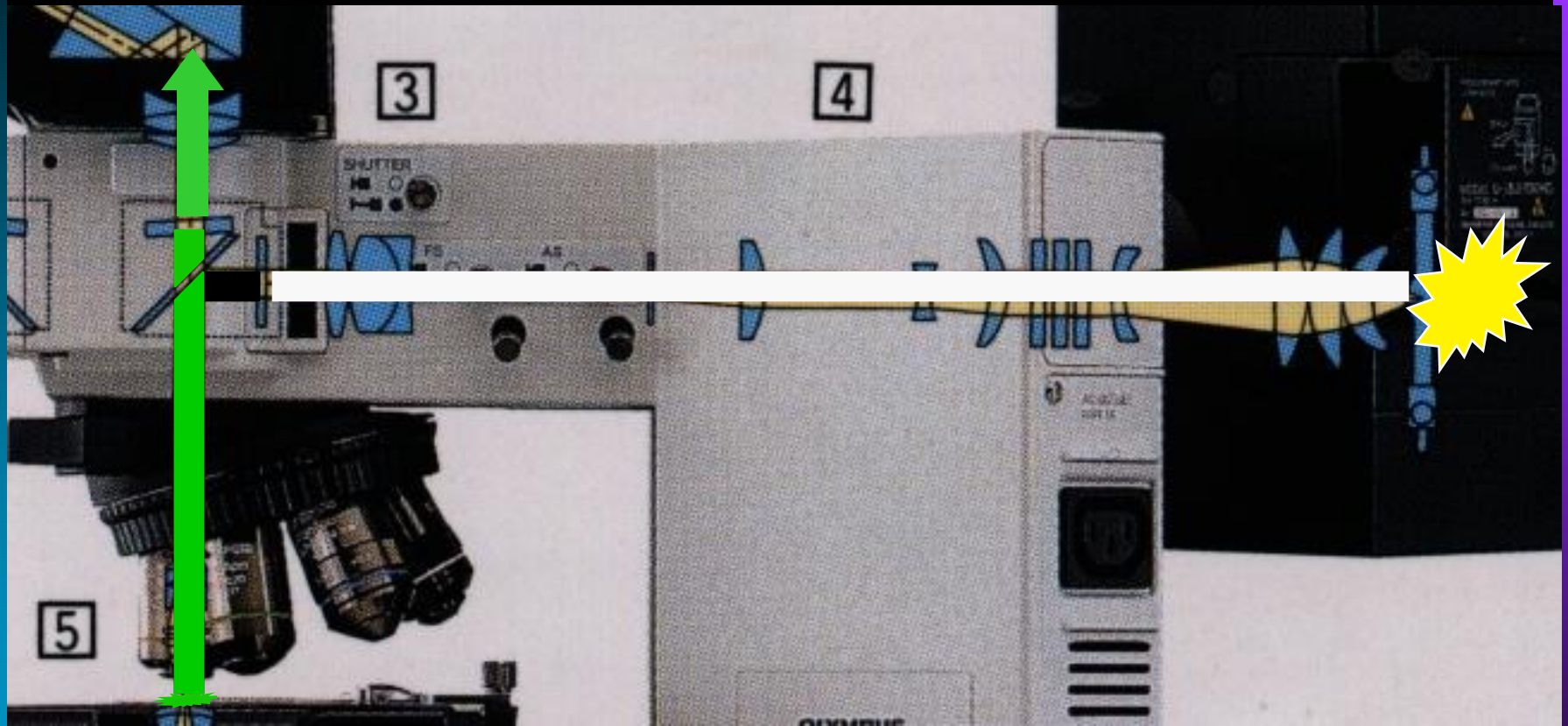
미분간섭 관찰
(광학원리)



Sample Image(형광 관찰)

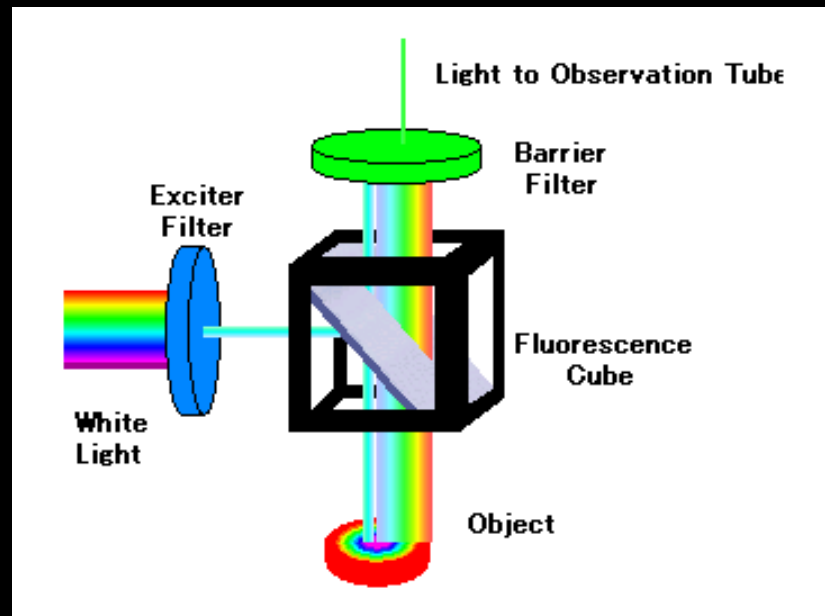


형광 CUBE의 이해

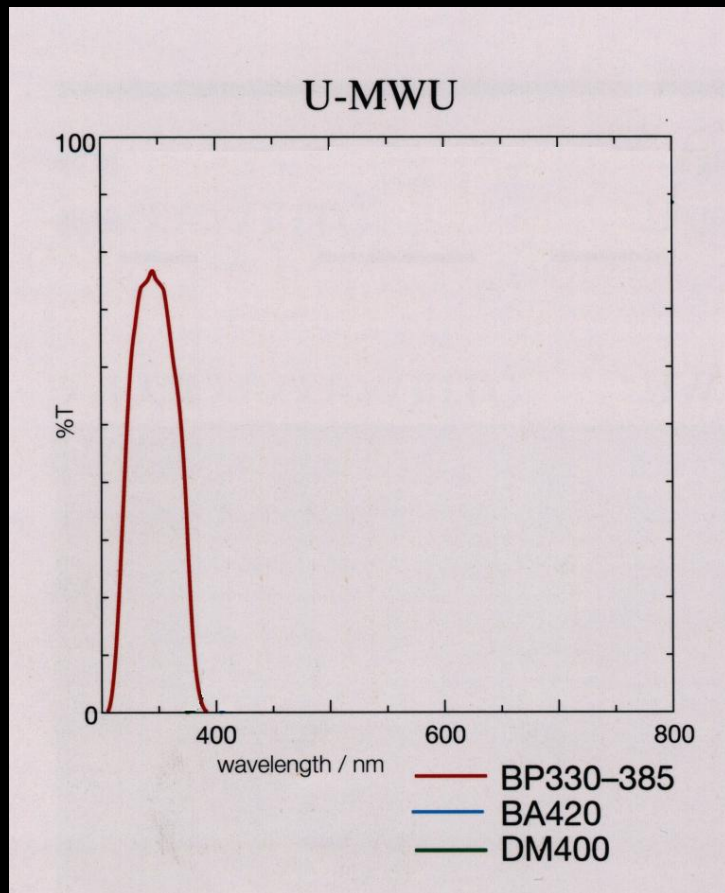


Fluorescence mirror unit

- Basic configuration
 - Excitation filter
 - Dichroic mirror
 - Emission filters



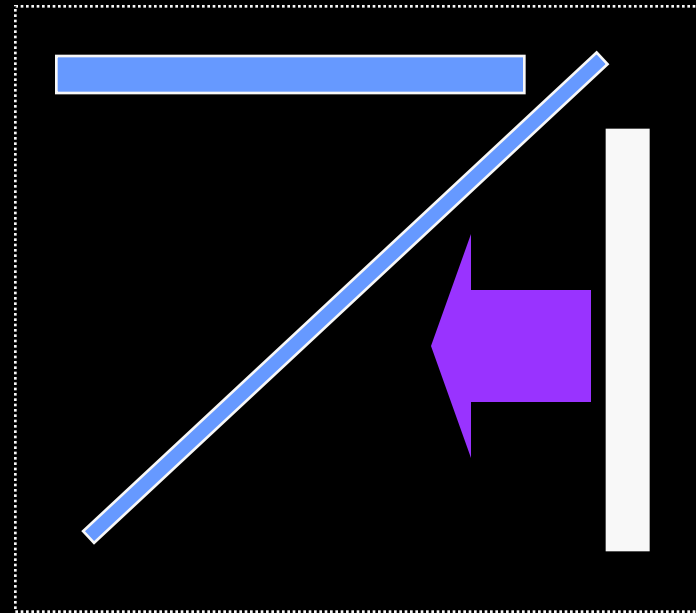
형광 CUBE의 활동 (여기 FILTER)



BAND PASS FILTER

흡수 FILTER

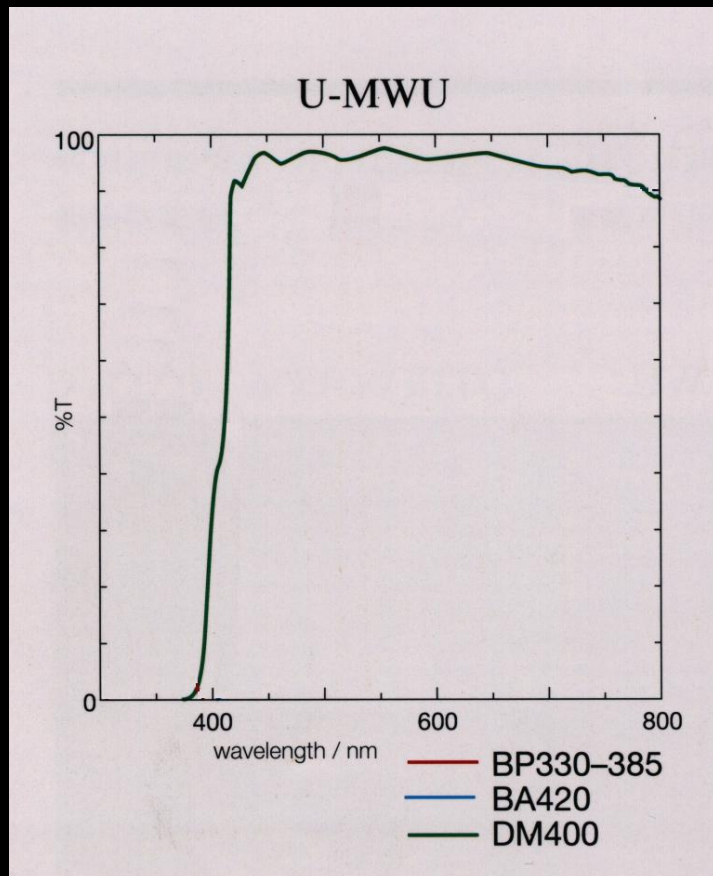
DICHROMICMIRROR



여기 FILTER

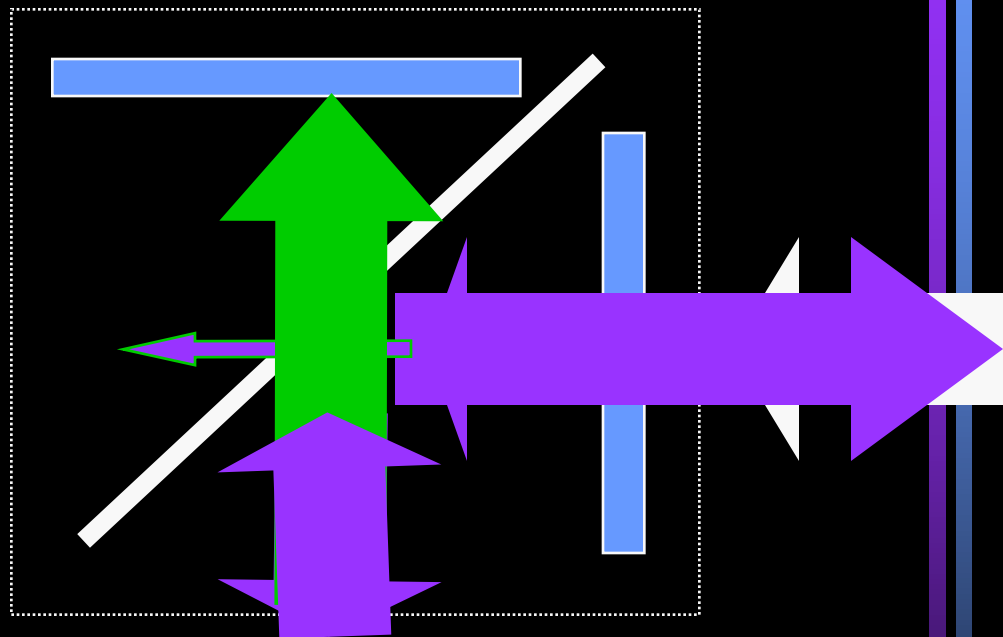
여기파장대의 光을 투과시킨다.

형광 CUBE의 역할 (DICHROMICMIRROR)



吸收 FILTER

DICHROMICMIRROR



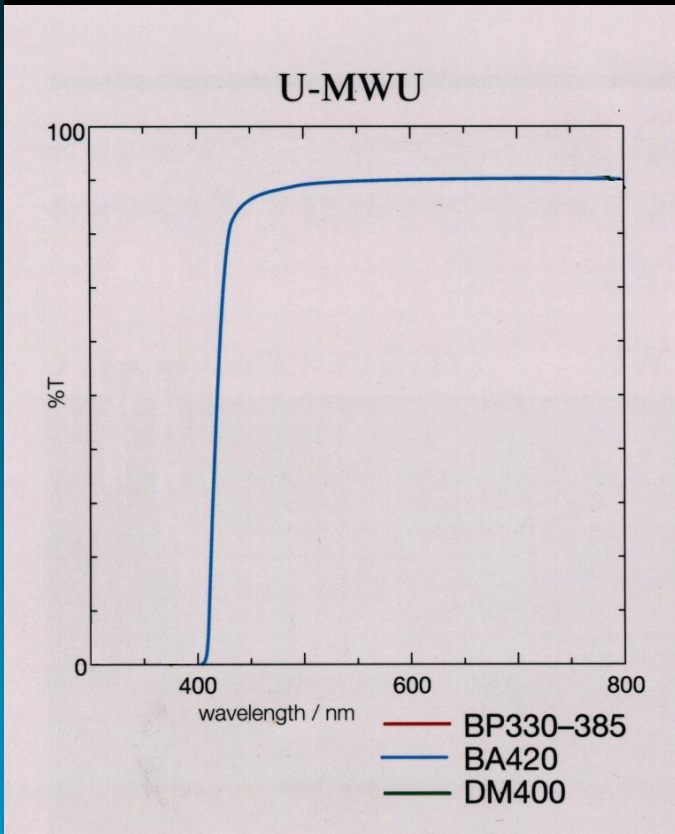
励起 FILTER

여기광을 반사한다.

형광은 투과한다

(미량의 여기광은 투과한다.)

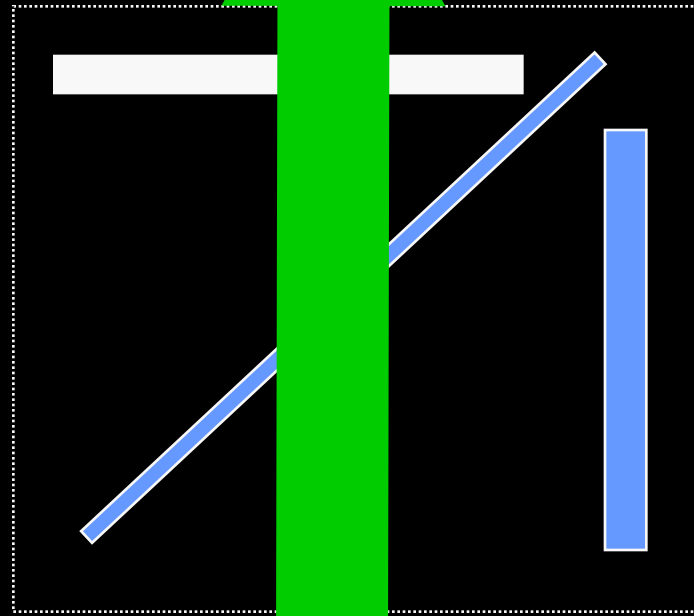
형광 CUBE의 역할 (흡수 FILTER)



BARRIER FILTER

흡수 FILTER

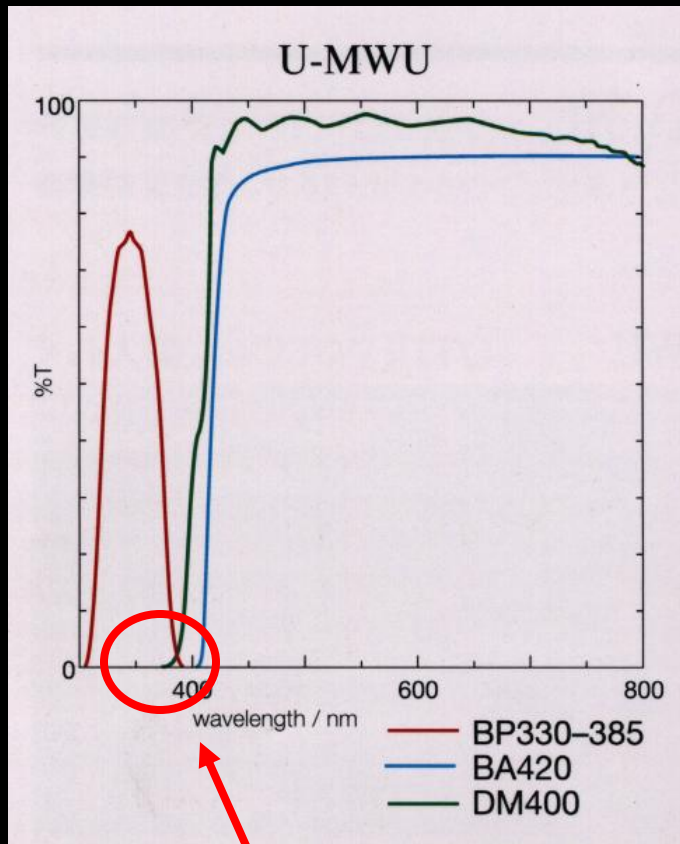
DICHROMIC MIRROR



勵起 FILTER

여기광을 안전하게
차단하고 형광만을
투과한다.

형광 CUBE의 파장특성



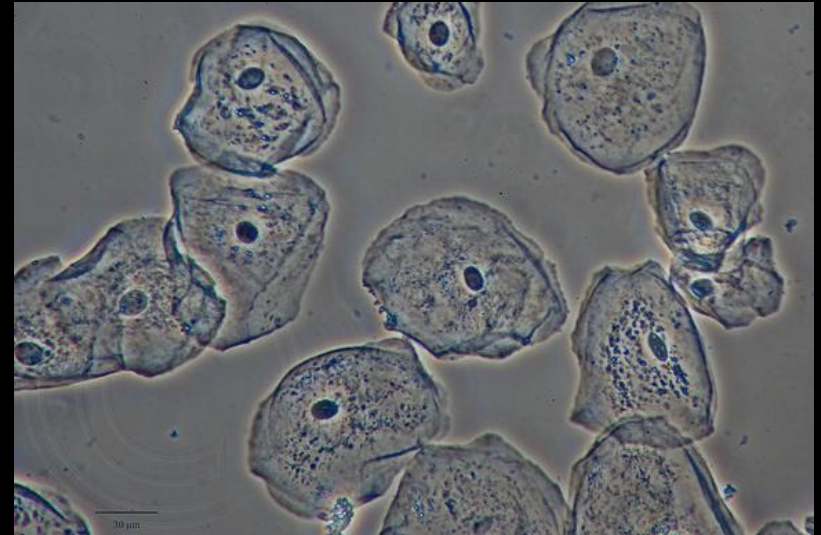
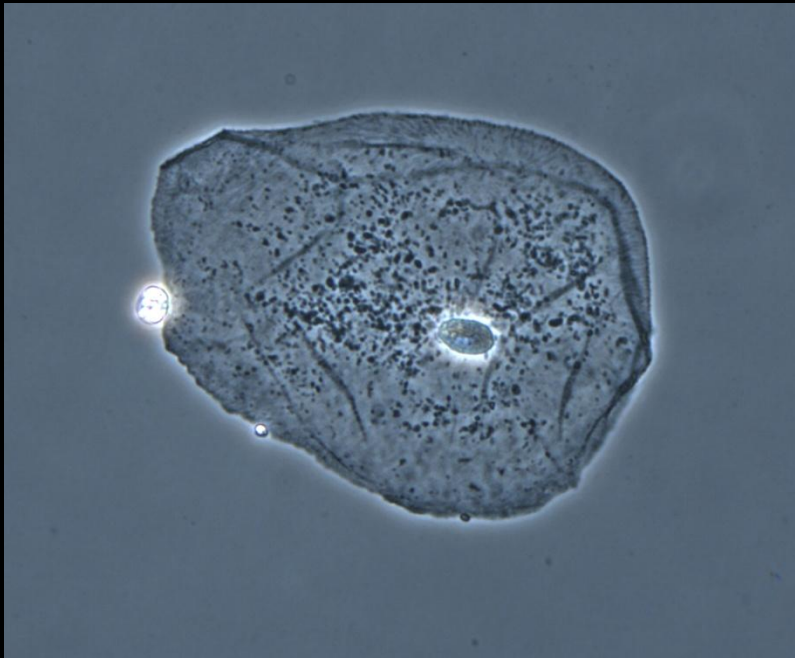
여기 FILTER,
DICHROICMIRROR,
흡수FILTER의 파장성능을
하나로 통합한것이다.

형광색소와의 적합성을
고려하여 사용

실제로의 여기광, 형광의
spectrum과 다른것을
주의하여야 한다.

이러한 CROSS OVER가 있기 때문에、吸収 FILTER가 必須

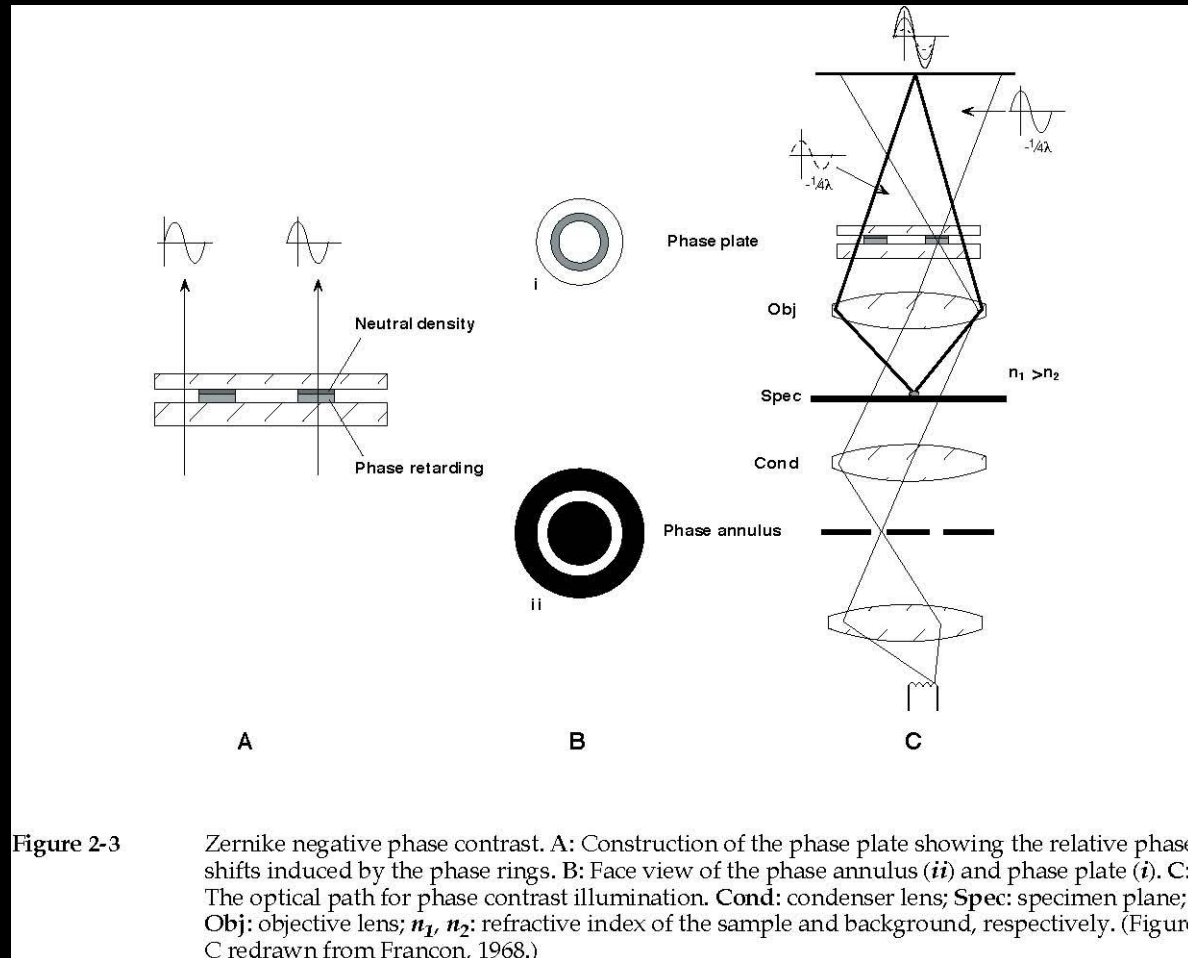
Sample Image(Phase Contarst)



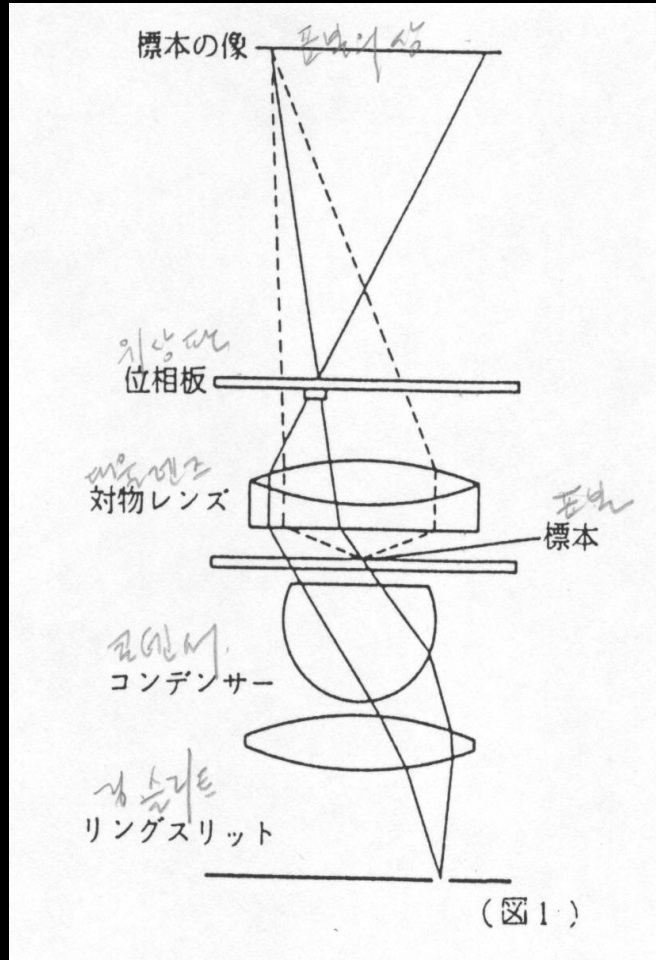
비교 이미지 (위상차 관찰법과 다른 관찰법)



위상차 관찰법 구조



위상차 현미경 (Phase-contrast Microscopy)



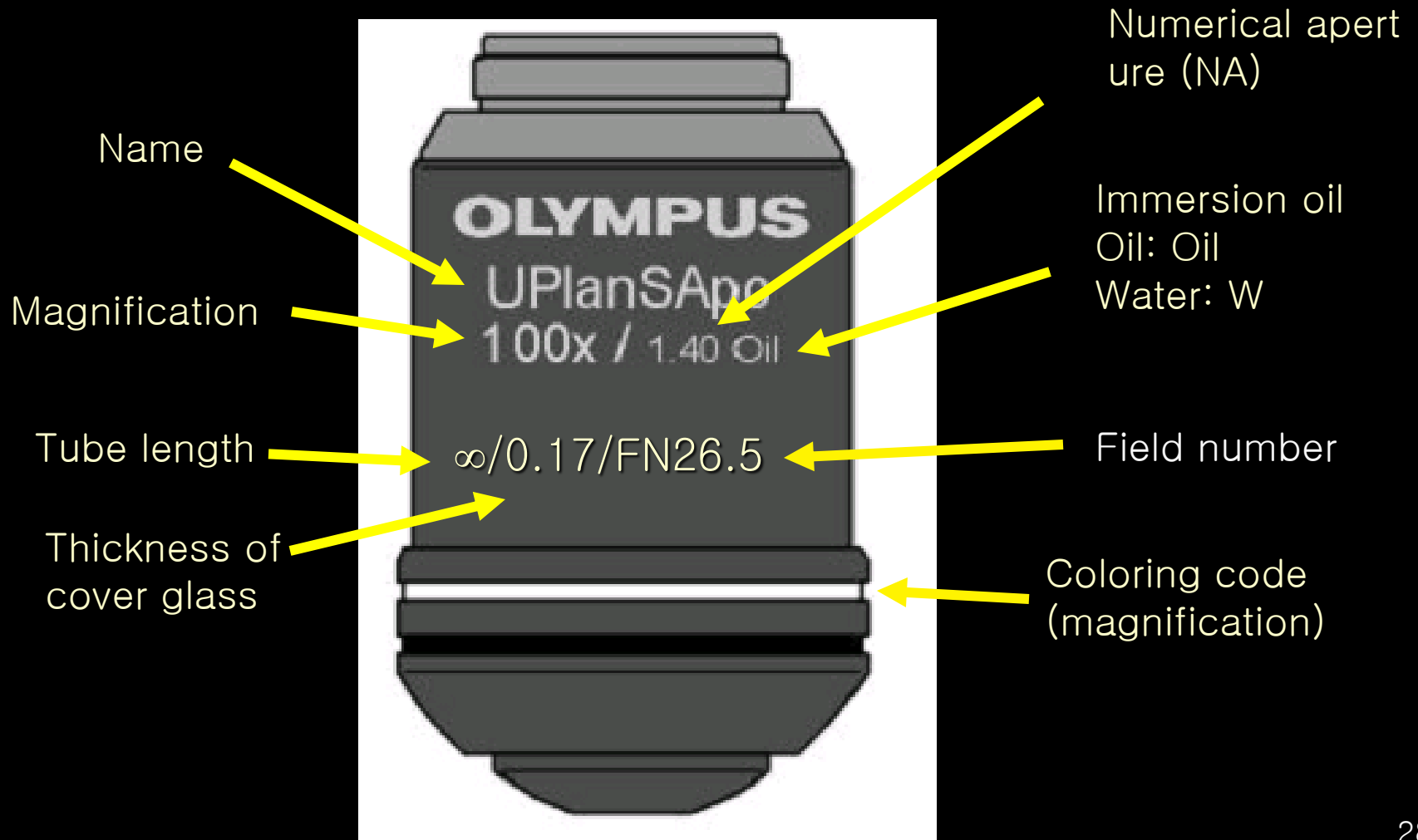
- ① 링 슬릿(Ring slit)에서의 빛으로 비추어진 표본의 입자는, 직진광과 입자에 의해 생긴 회절광과의 합성파에 의해 상을 만듦
- ② 입자가 극히 적고 투명하므로 매질보다 조금 굴절율이 클 경우, 입자의 상을 만드는 합성파는 주위를 통과한 광파보다 위상이 늦어짐. 이것은 회절광이 직진광보다 약 1/4파장만 늦어지기 때문임.

Explanation of Indication on the Objectives

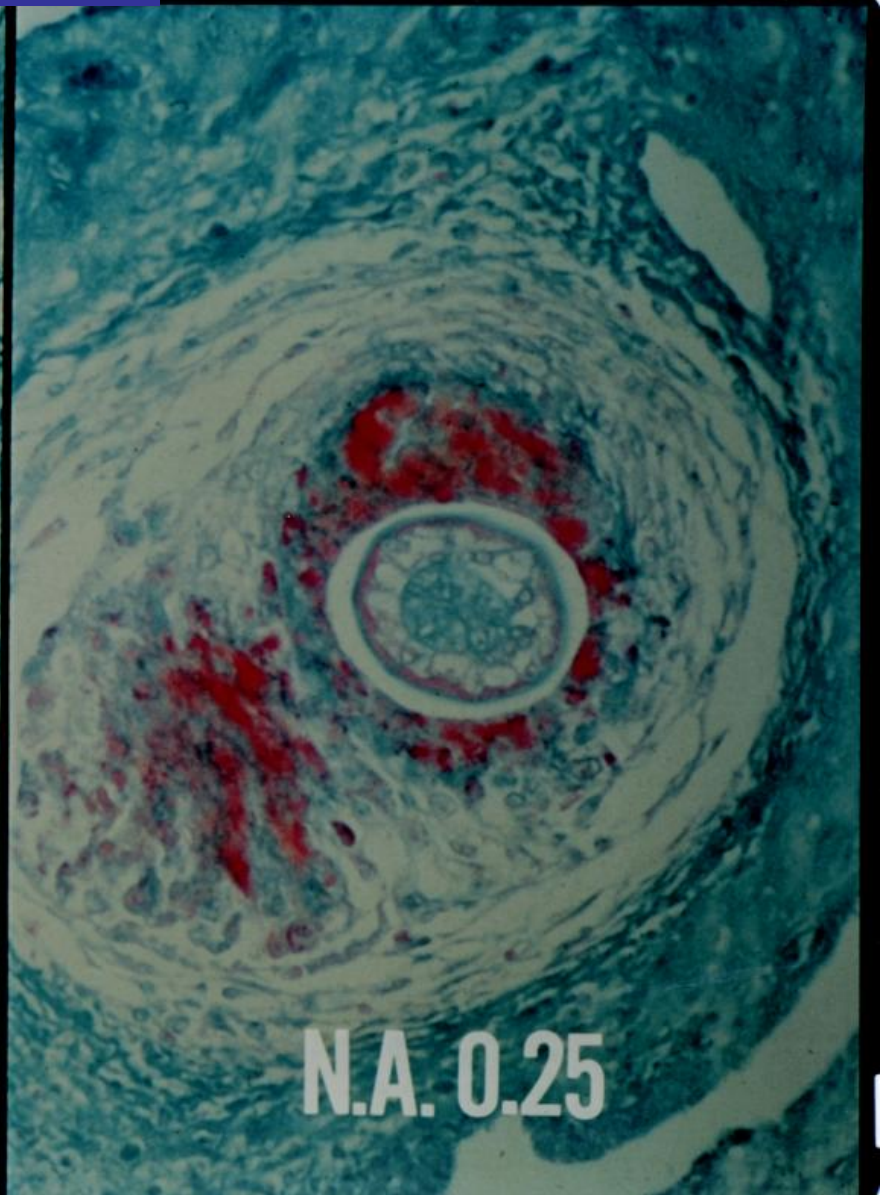
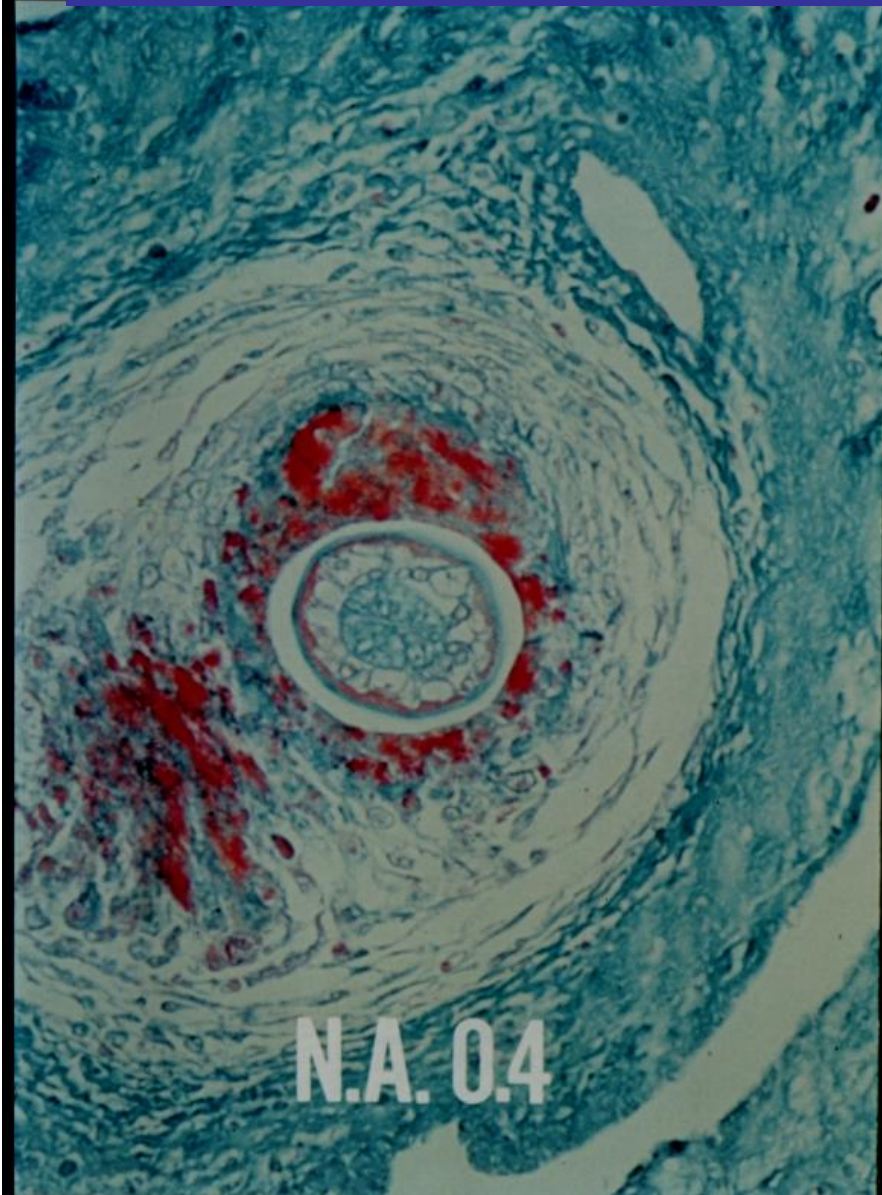


Indication on the objective lens (UIS2)

- Descriptions of markings*



NA and Resolution

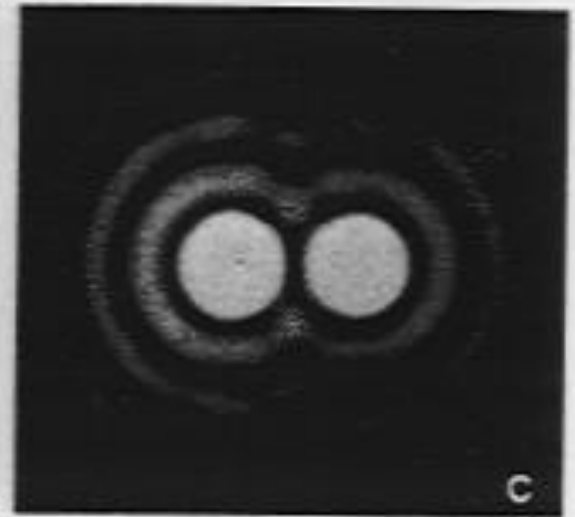
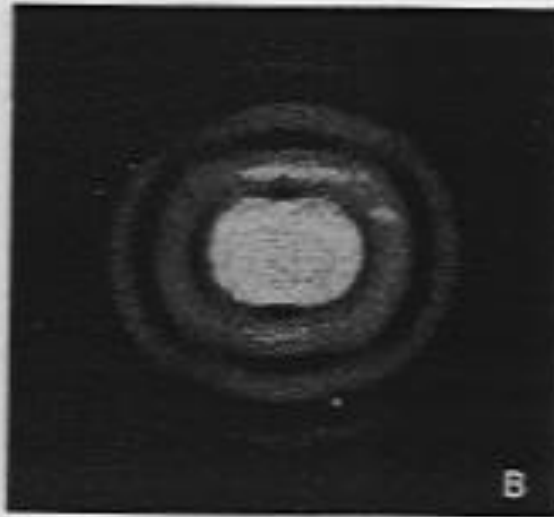
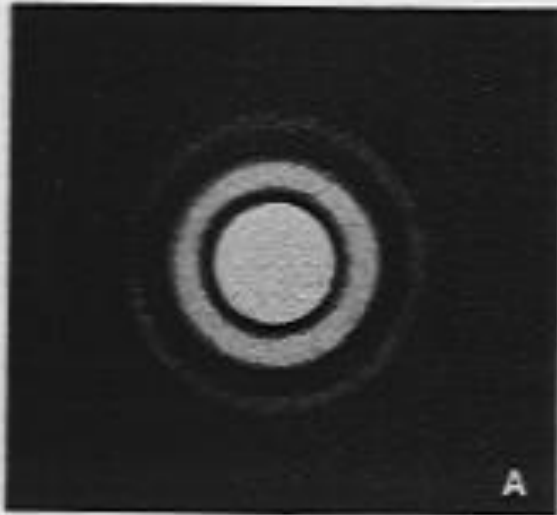


[분해능]

Resolving Power

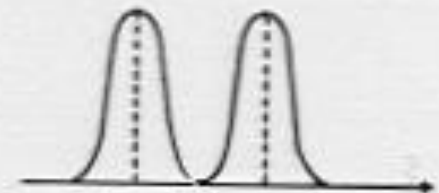
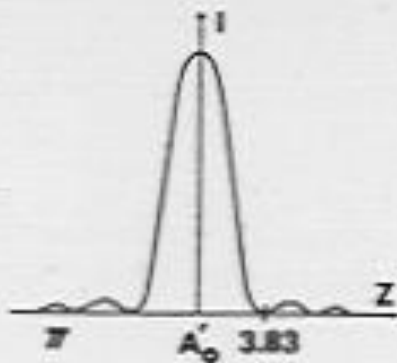
- 두 개의 점이 가까이 있을 때, 그 두 점을 두 점으로 인식이 가능한 최소의 간격이며, N.A.가 큰 만큼, 좋은 분해능을 얻을 수 있다.
- 분해능의 식
- $\varepsilon = 0.61 * \lambda / \text{N.A.}$ (Reyleigh fomula)
- λ : 사용파장이며 가시광의 경우에는 일반적으로 $0.55\mu\text{m}$ 파장을 기준으로 계산한다.
- ex.
- UMPLFL100x(N.A.=0.95), $\lambda = 0.55\mu\text{m}$
- $\varepsilon = 0.61 * 0.55\mu\text{m} / 0.95 = 0.35\mu\text{m}$

Point Spread Function & Resolution

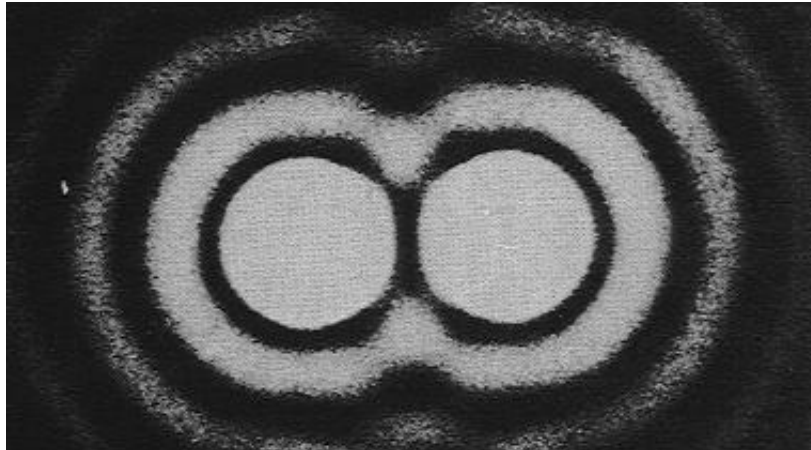


Not resolved

Resolved

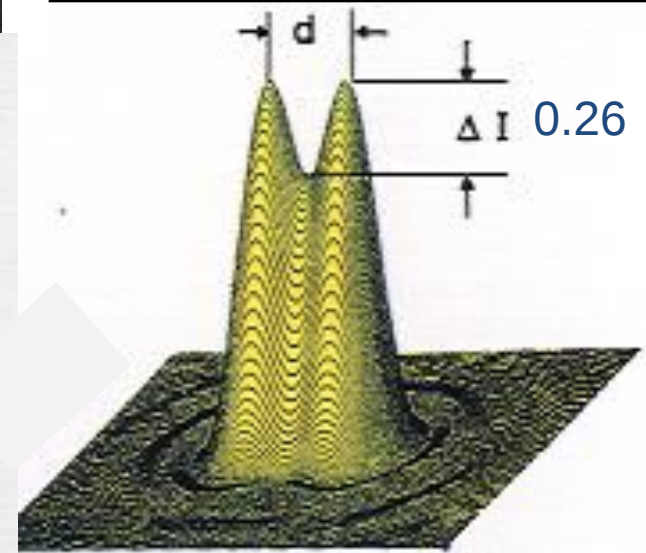
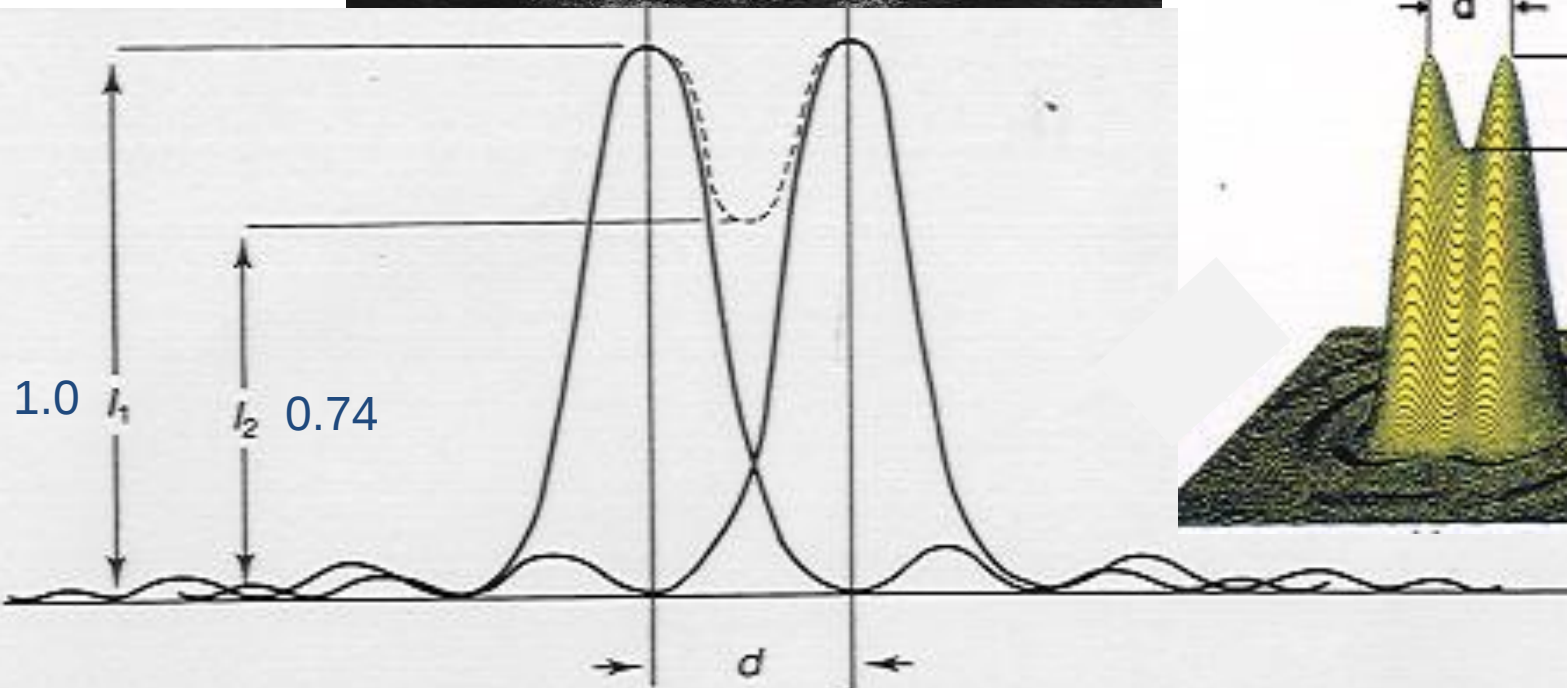


Resolving Power



$$d = 0.61 \frac{\lambda}{NA}$$

λ : Wavelength
 NA : Numerical Aperture



[W.D.-작동거리]

Working Distance

- Sample에 초점(focus)을 맞추고 난 후 대물렌즈 끝단에서 Sample (Cover glass를 이용하는 대물렌즈의 경우에는 cover glass 윗면)까지의 거리를 가르킨다.

[초점심도]

Focal Depth

- 현미경에서 초점이 맞추어진 위치에서 대물렌즈와 sample과의 거리를 변화시켜도 일정 범위안에서는 상이 선명하게 보인다. 이러한 일정 범위를 초점심도(focal depth)라고 말한다. 인간의 눈 또한 개개인에 따라 초점을 맞추는 능력에 차이가 있다.
- 현재, 초점 심도를 계산하기 위해서는 일반적으로 Berek 의 공식이 사용되어 지고 있다.
- 초점심도의 식 - 육안관찰의 경우 (Berek의 식)
- $$\Delta = (\omega * 250,000) / (N.A. * M) + \lambda / (2 N.A.^2)$$

ω : 눈의 분해능 0.0014(광학 각도가 0.5도 일 경우)
 M : 종합배율 (대물렌즈 * 접안렌즈배율)
- ex. UMPLFL100*, WH10*;
- $$\Delta = 350 / (0.95 * 1000) + 0.275 / 0.9 = 0.35 + 0.3 = 0.67 \mu m$$